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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO	
10/649,586	08/26/2003	Huy A. Bui	12671-035001	4993	
26181 75	90 07/11/2005		EXAMINER		
FISH & RICHARDSON P.C.			GURZO, PAUL M		
PO BOX 1022 MINNEAPOLIS	S, MN 55440-1022		ART UNIT	PAPER NUMBER	
			2881		
			DATE MAILED: 07/11/200	5	

Please find below and/or attached an Office communication concerning this application or proceeding.

		Applica	tion No.	Applicant(s)	\sim				
Office Action Summary		10/649,	586	BUI, HUY A.	(m)				
		Examin	er	Art Unit					
		Paul Gu		2881					
: Period for I	The MAILING DATE of this communi Reply	cation appears on t	he cover sheet wit	h the correspondence add	ress				
THE MA - Extension after SIX - If the period of the period	RTENED STATUTORY PERIOD FOR MILING DATE OF THIS COMMUNIONS of time may be available under the provisions (6) MONTHS from the mailing date of this commit ind for reply specified above is less than thirty (30 riped for reply is specified above, the maximum state of reply within the set or extended period for reply by received by the Office later than three months at latent term adjustment. See 37 CFR 1.704(b).	CATION. of 37 CFR 1.136(a). In no equication. b) days, a reply within the statutory period will apply and will, by statute, cause the a	event, however, may a re latutory minimum of thirty will expire SIX (6) MONT pplication to become ABA	ply be timely filed (30) days will be considered timely. FHS from the mailing date of this com ANDONED (35 U.S.C. § 133).	nmunication.				
Status									
1)⊠ R	esponsive to communication(s) file	d on <i>25 April 2005</i> .							
	☐ This action is FINAL . 2b)☑ This action is non-final.								
3)□ Si	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.								
Disposition	of Claims								
4a 5)☐ Cl 6)⊠ Cl 7)☐ Cl	Claim(s) is/are objected to.								
Application	Papers								
10)⊠ Th Ap Re	e specification is objected to by the e drawing(s) filed on 26 August 20 oplicant may not request that any object oplicant drawing sheet(s) including e oath or declaration is objected to	03 is/are: a)⊠ acc tion to the drawing(s) the correction is requ	be held in abeyand ired if the drawing(s	ce. See 37 CFR 1.85(a). s) is objected to. See 37 CFF	R 1.121(d).				
Priority und	der 35 U.S.C. § 119								
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 									
Attachment(s)									
2) 🔲 Notice o 3) 🔯 Informat	f References Cited (PTO-892) f Draftsperson's Patent Drawing Review (P [*] ion Disclosure Statement(s) (PTO-1449 or I o(s)/Mail Date <u>6/28/04</u> .	ΓΟ-948) PTO/SB/08)	Paper No(s)	ummary (PTO-413) /Mail Date formal Patent Application (PTO- 	152)				

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DETAILED ACTION

Election/Restrictions

Applicant's election without traverse of claims 1-18 and 20-46 in the reply filed on 4/25/05 is acknowledged.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-18 and 20-46 are rejected under 35 U.S.C. 103(a) as being unpatentable over Lennon et al. (6,804,410) in view of Schamber et al. (6,683,316).

Regarding claims 1-4, 20-23, 410 teaches a method of and computer program for calibrating an ion source, the ion source including a sample control system (62) including a sample holder (56) for supporting a sample plate (54) in a sample plane and a laser source (52) having a focal point representing a point at which a beam generated by the laser source intersects the sample plane, the method comprising mounting a sample plate in the sample holder, the sample plate including one or more target regions, determining a relationship between a coordinate system of the sample plate and a coordinate system of the sample control system, and using a determined relationship to align a target region of the sample plate with ion optics of a mass spectrometer (50) for a mass spectrometric analysis (col. 4, line 48 - col. 7, line 50 and Fig. 5 and 6).

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410 does not explicitly teach the relationship being determined at least in part by aligning one or more fiducials relative to a reference point of the sample control system, the fiducials defining reference points of the sample plate coordinate system. However, 316 teaches the sample plate can be moved based on the relationship between the sample plate coordinate system and sample control coordinate system. Further, one or more fiducial marks provided on the sample plate can be used to establish the scale of the optical image. These marks are used to relate coordinates of the optical image (sample control system) with coordinates of the stage driver (and therefore the sample plate coordinate system) (col. 13, line 23 - col. 14, line 67 and Fig. 1-8). This determined relationship can easily be used in a system that includes a mass spectrometer because alignment of the target region and the sample control system is widely realized in mass spectrometry much like in the teaching of 410. Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to align fiducials relative to a reference point of the sample control system to ensure that accurate implantation and subsequent analysis occurs.

Regarding claims 5, 6, 18, 24, 25, and 37 it is obvious that the fiducials form the target location because it is the target location that is used to determine the alignment. Further, the fiducials, and therefore the target regions, can be in any desired location and/or shape.

Regarding claims 7-9, 11, 26-28, and 30, 316 teaches the use of a first and second fiducial and these fiducials are used in processing the respective images. Further, these images are then used to position the beam accurately through aligning the fiducial marks with the sample control system. This positioning can only be accomplished if some type of alignment error step is present because there must be a step that determines if the beam and sample are aligned. If

they are not aligned, the fiducial marks and subsequent images must be reanalyzed to correct for any alignment error, thus achieving the alignment goal of the prior art (col. 13, line 23 - col. 14, line 67).

Regarding claims 12-15 and 31-34, the above applied prior art teaches the need for aligning the laser point to the reference point on the sample plate through the sample control system as stated above. Therefore, it is obvious that the laser's focal point is calibrated because the only way that the laser beam can strike the desired location on the sample plate is if it properply aligned and focused. Without such a step accurate beam intersection with the sample plate would not be possible.

Regarding claims 16, 17, 35, and 36, it is obvious that one or more offsets can be used because the coordinate systems of the sample plate and sample control system operates by using the relationship between the two to determine what, if any, offset exists, and then aligning and calibrating the laser the reduce that offset to as small as possible so that precise beam intersection with the sample plate will occur.

Regarding claims 38, 39, and 43, 410 teaches a mass spectrometry system comprising an ion source including a sample control system (62) including a sample holder (56) for supporting a sample plate (54) in a sample plane and a laser source (52) having a focal point representing a point at which a beam generated by the laser source intersects the sample plane, a processing unit configured to perform operations and mass spectrometric analysis (col. 4, line 48 - col. 7, line 50 and Fig. 5 and 6).

410 does not explicitly teach the relationship being determined at least in part by aligning one or more fiducials relative to a reference point of the sample control system, the fiducials

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defining reference points of the sample plate coordinate system. However, 316 teaches the sample plate can be moved based on the relationship between the sample plate coordinate system and sample control coordinate system. Further, one or more fiducial marks provided on the sample plate can be used to establish the scale of the optical image. These marks are used to relate coordinates of the optical image (sample control system) with coordinates of the stage driver (and therefore the sample plate coordinate system) (col. 13, line 23 - col. 14, line 67 and Fig. 1-8). This determined relationship can easily be used in a system that includes a mass spectrometer because alignment of the target region and the sample control system is widely realized in mass spectrometry much like in the teaching of 410. Finally, at least one of the fiducials must be positioned at a determinable displacement from the target location because one could not use the fiducial information if he did not know where the fiducial was in relation to the target location.

Regarding claims 40-42 and 44-46, it is obvious that the target region can provide at least one of the fiducials because the fiducial can be located at any point on the sample. Further, 410 teaches the use of a MALDI source and MALDI deposits eluent in a track and operates in a high pressure liquid chromatograph.

Allowable Subject Matter

Claims 10 and 29 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims. The above applied prior art does not teach or render obvious the claimed third fiducial that is used to align the reference point and to determine the alignment error of the coordinate system relative to the third fiducial.

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Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Paul Gurzo whose telephone number is (571) 272-2472. The

examiner can normally be reached on M-Fri. 7:30 - 6:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, John Lee can be reached at (571) 272-2477. The fax phone numbers for the

organization where this application or proceeding is assigned are (703) 872-9306 for regular

communications and (703) 872-9306 for After Final communications.

Information regarding the status of an application may be obtained from the Patent

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system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

PMG

JOHN R. LEE

SUPERVISORY PATENT EXAMINER

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